



1

DECLARATION

As the below-named inventors, we declare that:

Our residences, post office addresses, and citizenships are as stated below under our names.

We believe we are the original, first, and joint inventors of the subject matter claimed and for which a patent is sought on the invention entitled "METHOD AND APPARATUS FOR CONTROLLING RADIATION BEAM INTENSITY DIRECTED TO MICROLITHOGRAPHIC SUBSTRATES," the specification of which was filed in the U.S. Patent and Trademark Office on August 30, 2001 and assigned application number 09/945,316, confirmation number 1351 (Attorney Docket No. 108298547US).

We have reviewed and understand the contents of the above-identified specification, including the claims, as amended by any amendment specifically referred to above.

We acknowledge our duty to disclose information which is material to the patentability of this application in accordance with 37 C.F.R. § 1.56(a).

We further declare that all statements made herein of our own knowledge are true and that all statements made on information and belief are believed to be true; and further, that these statements were made with the knowledge that the making of willfully false statements and the like is punishable by fine or imprisonment, or both, under Section 1001 of Title 18 of the United States Code, and may jeopardize the validity of any patent issuing from this patent application.

Ulrich Boettiger

Date 12/6/01

Residence : City of Boise

State of Idaho

Citizenship : Germany

P.O. Address : 5109 North Lakemont Lane

Boise, Idaho 83703

Scott L. Light

Date 12/6/01

Residence : City of Boise

State of Idaho

Citizenship : United States of America

P.O. Address : 348 Sunburst

Boise, Idaho 83709